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IN THE UNITED STATES
PATENT AND TRADEMARK OFFICE

PATENT APPLICATION

OFFICIAL

Applicant: Khan et al. Case: APPM 5230/ETCH/SILICON/JB1
Serial No.: 09/866,313 Filed: May 24, 2001
Examiner: Duy Vu Nguyen Deo Group Art Unit: 1765
Title: METHOD OF ELIMINATING NOTCHING WHEN ANISOTROPICALLY
ETCHING SMALL LINEWIDTH OPENINGS IN SILICON ON
INSULATOR

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SUBMISSION UNDER 37 C.F.R. §1.114

S I R:

This Submission accompanies a Request for Continued Examination filed simultaneously herewith. This is in response to the Final Office Action (Paper No. 12) mailed August 27, 2003. Please amend the above identified patent application as follows: